

Q. Metrology, Inspection, and Yield Enhancement 분과

Room A
창의관 (106)

일 시 : 2월 17일(금) 11:20-12:35

세션명 : [FA2-Q] Q I

좌 장 : 김진승(전북대학교), 오승철(SNUprecision)

FA2-Q-1 11:20-11:50 **[Invited]**The Present Status and New Applications of Non-contact Corona-kelvin Dielectric Metrology, and Advanced Contamination Monitoring Techniques

저자: Lubek Jastrzebski and Andrew Findlay
소속: Semilab Co., Ltd.

FA2-Q-2 11:50-12:20 **[Invited]**2D Spectroscopic Ellipsometer

저자: Anlun Tang and J. L. Choi
소속: AUROS Technology, Inc.

FA2-Q-3 12:20-12:35 3D Profile Measurement of TSVs based on the Optical Comb of a Femtosecond Pulse Laser

저자: 진종한^{1,2}, 이성현¹, 김재완^{1,2}, 강주식^{1,2}, 김종안¹
소속: ¹한국표준과학연구원 기반표준본부 길이센터,
²과학기술연합대학원대학교

FA2-Q-4 12:35-12:50 Defect Signal Intensity Simulation by Change of Apertures on a Bright Field Inspection Tool

저자: Seong-Min Ma, Kyu Young Kim, Dae Jong Kim, Young Jae Cho, Sung Su Kim, Hyung Won Yoo, and Il Keoun Han
소속: Manufacturing Division, Hynix Semiconductor Inc.